

AF/1756  
IFW



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application No. : 10/054,259 Confirmation No. 7049  
Applicant : Ronald M. Kubacki  
Filed : January 22, 2002  
TC/A.U. : Art Unit 1756  
Examiner : Kathleen DUDA  
Docket No. : 02-103  
Customer No. : 24026  
Title : Capacitor with Plasma Deposited Dielectric

**AMENDMENT AFTER FINAL REJECTION**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

To the Honorable Commissioner for Patents:

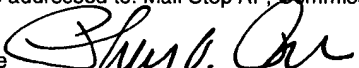
This amendment is in response to the FINAL Office action dated May 25, 2004, and is being filed within two months of the mailing date of the final office action.

**Amendments to the Claims** are reflected in the listing of claims, which begin on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.

**CERTIFICATE OF MAILING UNDER 37 CFR 1.8(a)**

I hereby certify that this paper, along with any paper referred to as being attached or enclosed, is being deposited with the United States Postal Service on the date indicated below, with sufficient postage, as first class mail, in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Signature 

Printed Name Philip O. Post

Date JUNE 4, 2004